## Docket No. TRANSMITTAL OF FORMAL DRAWINGS FR919990065 approved ON 10/16/03 B ulenger In Re Application Of: Confirmation No. Examiner Serial No Date 2822 09/756,997 01-08-01 6885 Christy L. Novacek METHOD FOR ELIMINATING DEVELOPMENT RELATED DEFECTS IN PHOTORESIST MASKS Invention: Address to: **Assistant Commissioner for Patents** Washington, D.C. 20231 Transmitted herewith are: 2 sheets of formal drawing(s) for this application. $\boxtimes$ Each sheet of drawing indicates the identifying indicia suggested in 37 CFR Section 1.84(c). Dated: Joseph P. Abate Registration No. 30,238 I certify that this document and attached formal drawings Telephone No. 845-894-4633 8/19/03 are being deposited on Fax No. 845-892-6363 U.S. Postal Service as first class mail under 37 C.F.R. 1.8 and addressed to the Assistant Commissioner for Patents, Washington, D.C. 20231

Signature of Person Mailing Correspondence

Typed or Printed Name of Person Mailing Correspondence

hereby certify that this correspondence is being deposited with the United States Post fice as first class mail in an enveloped addressed to: Commissioner of Patents, P. O. fox 1450, Arlington, VA 22313-1450, on

Depositor: Karen Cinq-Mars

nais 8/19/03

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of \_\_\_:

August 15, 2003

<u>Caroline Boulenger</u> : Group Art Unit: 2822

<u>Serial No. 09/756,997 : </u>

Examiner: Christy L. Novacek

Filed: 01-08-01

IBM Corporation

Title: METHOD FOR ELIMINATING

Dept. 18G/Bldg. 300-482

DEVELOPMENT RELATED DEFECTS

2070 Route 52,

IN PHOTORESIST MASKS

Hopewell Junction, NY 12533

LETTER

Commissioner of Patents P. O. Box 1450 Alexandria, Va 22313-1450

Sir:

Applicant intends to submit an additional Supplemental Information Disclosure statement within the next 30 - 45 days. Deference of continued examination is requested until such Supplemental Information Disclosure is filed.

Respectfully submitted,

Joseph P Registration No. 30,238

Telephone No. (845) 894-4633

09/756,997